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Future Normal in Semiconductor

2025-02-13(목), 15:50-17:20

좌장: 추후업데이트 예정

D. Thin Film Process Technology 분과

[TB3-D] Emerging Films Growth - III

초청 TB3-D-1 16:50-17:05	Dimensional Scaling of Transition Metal Phosphides for Advanced Interconnect Gangtae Jin Gachon University
TB3-D-2 16:20-16:35	The Novel Microstructure Design with Nanowire-Bundled Grain Boundaries in Thermoelectric Materials via Atomic Layer Deposition Gwang Min Park ^{1,2} , Seong Keun Kim ^{1,2} , Seung-Hyub Baek ² , Jin-Sang Kim ² , Seunghyeok Lee ^{2,3} , Jinseok Hong ⁴ , Seokho Nahm ⁴ , Seung-Yong Lee ^{4,5} ¹ KU-KIST Graduate School of Converging Science and Technology, Korea University, ² Electronic Materials Research Center, Korea Institute of Science and Technology, ³ Department of Materials Science and Chemical Engineering, Hanyang University, ⁴ Division of Materials Science and Engineering, Hanyang University, ⁵ Department of Battery Engineering, Hanyang University
TB3-D-3 16:35-16:50	Composition-Controlled Hafnium-Based Inorganic/Organic Hybrid Dry Resist for EUV Lithography via Advanced Atomic Layer Deposition Kyungryul Ha, Dong Geun Kim, Hyekyung Kim, Ji-Hoon Ahn, Woo-Hee Kim, and Tae Joo Park Department of Materials Science and Chemical Engineering, Hanyang University
TB3-D-4 16:50-17:05	Molecular Layer Deposition of Tin-Based Organic-Inorganic Hybrid Films as Photoresists Dong Geun Kim, Kyungryul Ha, Hyekyung Kim, Woo-Hee Kim, Tae Joo Park, and Ji-Hoon Ahn Department of Materials Science and Chemical Engineering, Hanyang University
TB3-D-5 17:05-17:20	Interface Engineering for High Thermoelectric Performance via Atomic Layer Deposition of ZnO-TiO ₂ Multilayers Su Min Eun, Jin Kyeong Shin, Ye Jin Jeong, and Byung Joon Choi Department of Material Science and Engineering, Seoul National University of Science and Technology